U.S. UTILITY Patent Application

PATENT NUMBER and ISSUE DATE

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10080424	02/22/2002	438	166	2812	COLEMAN

**APPLICANTS: Hagino Takashi; Imao Kazuhiro; Wakita Ken; Monzen Toshio; Ogata Hidenori; Nakanishi Shiro; Morimoto Yoshihiro;

**CONTINUING DATA VERIFIED:

** FOREIGN APPLICATIONS VERIFIED:
JAPAN 2001-47181 02/22/2001

PG-PUB | DO NOT PUBLISH ☐ | RESCIND ☐

Foreign priority claimed ☐ yes ☐ no
35 USC 119 conditions met ☐ yes ☐ no
Verified and Acknowledged Examiners's intials

ATTORNEY DOCKET NO
YKI-0084

TITLE : Method for manufacturing polycrystalline semiconductor layers and thin-film transistors, and laser annealing apparatus

NOTICE OF ALLOWANCE MAILED	Assistant Examiner	CLAIMS ALLOWED: Total Claims / Print Claim for O.G
ISSUE FEE: Amount Due / Date Paid	Primary Examiner	DRAWING: Sheets Drwg. / Figs.Drwg. / Print Fig.
☐ TERMINAL DISCLAMER	PREPARED FOR ISSUE	Application Examiner

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